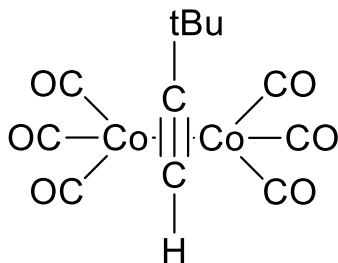


Catalog # 27-0770 (3,3-Dimethyl-1-butyne)dicobalt hexacarbonyl, 98% CCTBA



## Thermal Behavior:

- Vapor pressure: 0.1 Torr at 40 °C [7]
- Evaporation behavior studied in [11]

## Technical Notes:

1. Liquid cobalt carbonyl based precursor for the growth of cobalt metal and oxide thin films.

Target Deposit	Deposition Technique	Delivery Temperature	Pressure	Co-reactants	Deposition Temperature	Ref.
Co	CVD			H <sub>2</sub>	120-230 °C	[1, 10]
Co	CVD	20 °C	10 Torr	H <sub>2</sub>	150 °C	[3, 4]
Co	CVD	45 °C	0.3 Torr		300 °C	[6]
Co	PEALD	50 °C	0.05-2 Torr	H <sub>2</sub> plasma	100-250 °C	[2, 8, 9]
Co-organic	PECVD	60-150 °C in THF	0.3 Torr	He plasma		[5]
CoO	ALD	50 °C	9 Torr	O <sub>3</sub>	68-138 °C	[7]

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